
International Workshop on Plasma and Bionano Devices

Date: 14th November, 2018, Wednesday

Time: 19:00-21:10

Venue: Ishikawa Prefectural Bunkyo Hall **Room 401**

<http://www.bunkyo.or.jp/bunkyo/index.html> (The pages are given in Japanese.)

Organized by

Innovative Energy Research Center, Institute of Fluid Science, Tohoku University

Center of Plasma Nano-Interface Engineering, Kyushu University

Program: All speakers are invited speakers.

Chair: M. Shiratani, Kyushu University

1. 19:00-19:10

Opening remark

Prof. M. Shiratani, Kyushu University

2. 19:10-19:30

Defect-free nano-processes for bionano devices

Prof. S. Samukawa, Tohoku University

3. 19:30-19:50

First principles analysis of atomic precision processes

Peter Ventzek, TEL

4. 19:50-20:10

Atomic layer deposition: State of the art

Dr. T. Nozawa, ASM

5. 20:10-20:30

GaN HEMT

Prof. T. Suemitsu, Tohoku University

6. 20:30-20:50

Toward Improving Research Processes using Big Data

Prof. D. Ikeda, Kyushu University

7. 20:50-21:10

Big and small data analysis in plasma processes

Prof. M. Shiratani, Kyushu University
